EM Calibration Standards 3

Chessy SEM Calibration Specimen

Applications

Imaging

- Calibration of SEM magnification in all ranges between 20x and 50,000x
- Check of equal scaling in X and Y
- Check of orthogonality and distortion
- Resolution test at high magnification on the edges of the gold squares

Motorised stages

- Measurement of reproducibility using stored positions
- Calibration of readings in X and Y
- Calibration of stage orthogonality
- Measurement of absolute positioning accuracy

Experimental Electron Lithography

- Generation of metric writing fields between 10µm and 5mm square via mark recognition and alignment
- Measurement of SEM distortion at any magnification via mark recognition on different places
- Check of defocusing in outer areas

Structure

There are more than 1.6 million gold squares on 1 μ m size of silicon forming a 4-fold checkerboard pattern in an area 5mm square. The smallest metric checkerboard has a size of 10 x 10 μ m. Such checkerboards form large metric checkerboards of 100 x 100 μ m and these again form checkerboards of 1mm square. Finally such 1mm squares are arranged in the same manner covering a field of 5mm square.

The edges of the empty corners in 100 μ m checkerboards are additionally marked. The surrounding frame is 10 μ m wide and has an outer side length of 5.04mm.

C340 Chessy Calibration Specimen



